EPFL Ecole polytechnique fédérale de Lausanne EPFL MicroNanoFabrication Annual Review Meeting Philippe Flückiger, EPFL, May 7th, 2019

> Next editions ; 21st 05.05.2020 22nd 04.05.2021

EPFL Center of MicroNanoTechnology

EPFL-CMi | May 7th 2019

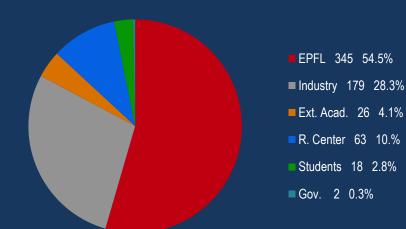
Welcome & thanks



- Welcome to the 20th edition of the CMi MicroNanoFabrication Annual Review Meeting
- 633 participants registered (with 30% from industry)
- Many thanks for your participation
- Global companies
- Local industry
- Startups
- Suppliers

SPEI

- Government Agencies
- Researchers
- Faculty members
- Colleagues from other academic cleanrooms



- -> Traveling from 11 different countries
- -> Networking

Outline



- Users
- Finances
- Governance
- Staff
- Cleanroom
- Tools
- Projects





Users in 2018



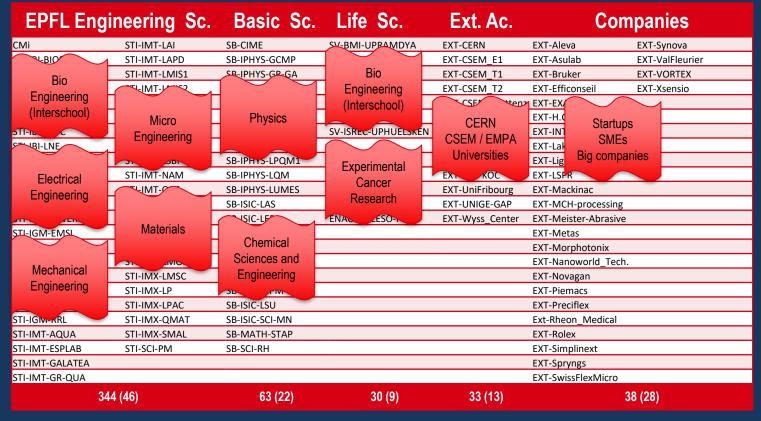
EPFL Engin	eering Sc.	Basic Sc.	Life Sc.	Ext. Ac.	Com	panies
СМі	STI-IMT-LAI	SB-CIME	SV-BMI-UPRAMDYA	EXT-CERN	EXT-Aleva	EXT-Synova
STI-IBI-BIOS	STI-IMT-LAPD	SB-IPHYS-GCMP	SV-GHI-UPKIN	EXT-CSEM_E1	EXT-Asulab	EXT-ValFleurier
STI-IBI-CLSE	STI-IMT-LMIS1	SB-IPHYS-GR-GA	SV-IBI-UPDEPLA	EXT-CSEM_T1	EXT-Bruker	EXT-VORTEX
STI-IBI-LBEN	STI-IMT-LMIS2	SB-IPHYS-LASPE	SV-IBI-UPLUT	EXT-CSEM_T2	EXT-Efficonseil	EXT-Xsensio
STI-IBI-LBNC	STI-IMT-LMIS4	SB-IPHYS-LEB	SV-IBI-UPOATES	EXT-CSEM-Muttenz	EXT-EXALOS	
STI-IBI-LBNI	STI-IMT-LMTS	SB-IPHYS-LPMC	SV-ISREC-UPGON	EXT-EMPA	EXT-H.Glass	
STI-IBI-LHTC	STI-IMT-LO	SB-IPHYS-LPMV	SV-ISREC-UPHUELSKEN	EXT-ETHZ_(APS)	EXT-INTEL	
STI-IBI-LNE	STI-IMT-LPMAT	SB-IPHYS-LPN		EXT-HEIG-VD-MNT	EXT-LakeDiamond	
STI-IEL-GR-SCI	STI-IMT-LSBI	SB-IPHYS-LPQM1		EXT-HESGE	EXT-Ligentec	
STI-IEL-LANES	STI-IMT-NAM	SB-IPHYS-LQM	IC-IINFCOM-LSI1	EXT-UNI-KOC	EXT-LSPR	
STI-IEL-LSM	STI-IMT-OPT	SB-IPHYS-LUMES		EXT-UniFribourg	EXT-Mackinac	
STI-IEL-NANOLAB	STI-IMX-FIMAP	SB-ISIC-LAS		EXT-UNIGE-GAP	EXT-MCH-processing	
STI-IEL-POWERLAB	STI-IMX-INE	SB-ISIC-LEPA	ENAC-IIC-LESO-PB	EXT-Wyss_Center	EXT-Meister-Abrasive	
STI-IGM-EMSI	STI-IMX-LMGN	SB-ISIC-LND			EXT-Metas	
STI-IGM-FLEXLAB	STI-IMX-LMM	SB-ISIC-LPDC			EXT-Morphotonix	
STI-IGM-LFMI	STI-IMX-LMOM	SB-ISIC-LPI			EXT-Nanoworld_Tech.	
STI-IGM-LRESE	STI-IMX-LMSC	SB-ISIC-LSCI			EXT-Novagan	
STI-IGM-MICROBS	STI-IMX-LP	SB-ISIC-LSPM			EXT-Piemacs	
STI-IGM-NEMS	STI-IMX-LPAC	SB-ISIC-LSU			EXT-Preciflex	
STI-IGM-RRL	STI-IMX-QMAT	SB-ISIC-SCI-MN			Ext-Rheon_Medical	
STI-IMT-AQUA	STI-IMX-SMAL	SB-MATH-STAP			EXT-Rolex	
STI-IMT-ESPLAB	STI-SCI-PM	SB-SCI-RH			EXT-Simplinext	
STI-IMT-GALATEA					EXT-Spryngs	
STI-IMT-GR-QUA					EXT-SwissFlexMicro	
344	(46)	63 (22)	30 (9)	33 (13)	3	8 (28)



- Total: 508 users operating the CMi tools
- (Total: 118 labs or companies)

Users in 2018



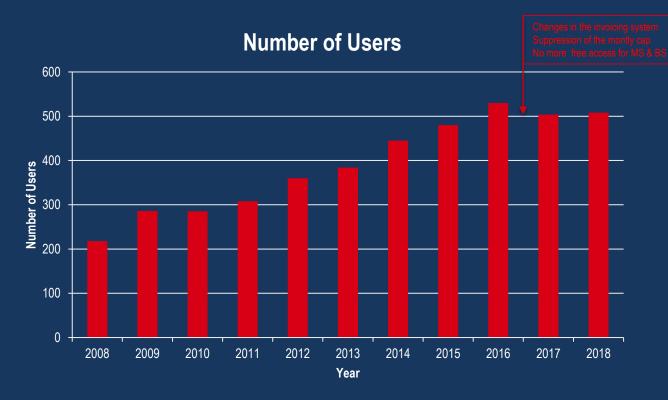




- Total: 508 users operating the CMi tools
- (Total: 118 labs or companies)

Users in 2018



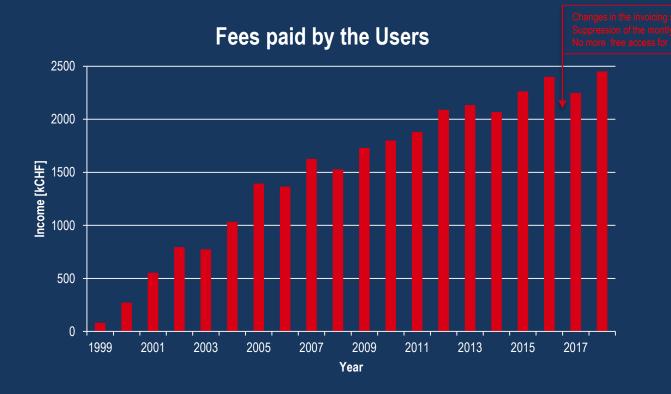




- In 2017 a correction of -5% occurred due to the changes in the invoicing system
- In 2018 we observe a growth of 1% (which is expected to strengthen) EPFL-CMi | May 7th 2019 6

Finances







- In 2017 a correction of -6% occurred due to the changes in the invoicing system.
- In 2018 we observe a growth of 9%.

Finances

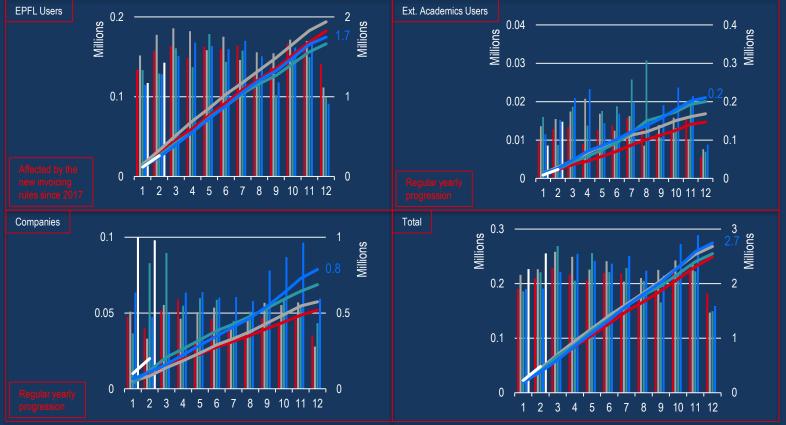


2015

2016

2017

2018 2019





- Monthly monitoring of the invoicing to the 3 categories of users
- Contribution from companies raised from 21% in 2015 to 29% in 2018 EPFL-CMI | M

Finances



- In summary
 A new invoicing system was introduced on October 1st 2016 based on transparent and auditable direct and indirect costs calculations in order to make our costs eligible to internal and external clients as well as to funding research bodies.
- Since then

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- The benefits
- CMi has now an SNSF compatible transparent cost accounting methodology (CMi bills are eligible)

No more free access for the master & semester projects (replaced now by capped subsidies)

No more cap per academic user and per month (previously CHF 1600.- / academic user / month)

• CMi has more available capacity, less bottlenecks on the tools

• Side effects

2018

- In 2017 a correction of the # of users (-5%) and of the fees paid by the users (-6%)
- In 2018 a growth of the # of users (+1%) and of the fees paid by the users (+9%)
- Estimated operating expense 2018 : 8MCHF
- Fees paid by the users 2018 : 2.5MCHF
- Operating result 2018 : 100 KCHF

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Governance

VP for Research Andreas Mortensen



EPFL



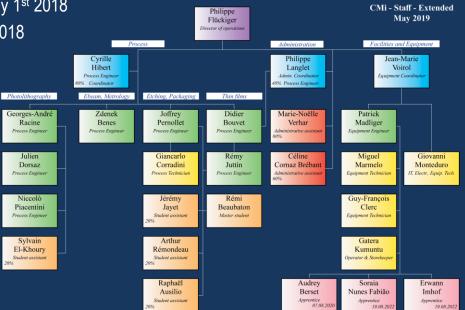
C ME EPFL Center of MicroNanoTechnology

- Since June 2017 the CMi reports to the Vice-President for Research (instead of reporting to the dean of the school of engineering)
- Our executive board is composed of 10 Professors including our president
- Members nominated for a period of 4 years from 01.11.2018 until 31.10.2022



- Staff composed of 17.6 FTE employees
- Whole staff under permanent positions since May 1st 2018
- 5 CDD were transformed into 5CDI on May 1st 2018
- Employ 4 student assistants (part time)
- Train 3 apprentices
- 1 trainee







New tools installed in 2019



- DUV Stepper lithography system Delivered 11.12.2018
 - ASML PAS 5500/350C (248nm)
 - SNSF R'Equip grant 206021-170750 Prof. Tobias Kippenberg
 - Resolution <150nm, Overlay accuracy <30nm, Productivity >100wph



7x Optical Microscopes – Delivered 26.02.2019
 Leica DM8000 M



- Film Thickness Measurement System Delivered 10.01.2019
 - + Filmetrics F54
 - Automatic mapping
 - + (Filmetrics was acquired by KLA in March 2019)





New tools installed in 2018

Stylus Profiler – Delivered 05.10.2018

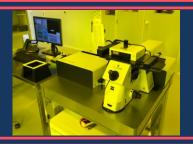
- KLA-Tencor AlphaStep D-600
- 2D and 3D step heights measurements
- From few nm to 1200um

3D Laser lithography System– Accepted 16.02.2018

- Nanoscribe Photonic Professional GT
- ETH Board SFA grant CERAMIC X.0 Prof. Jürgen Brugger
- Highest resolution commercially available micro 3D printer (x-y 300nm; z 800nm)
- Non-linear two-photon absorption process from an infrared femtosecond laser (780nm)

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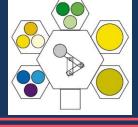
Tools under evaluation & Budget requests for 2019

DUV Photoresist Coater & Developer

- Dedicated to DUV stepper lithography
- Call for tender to be published in Q2 2019

Physical Vapor Deposition Cluster Tool (sputtering)

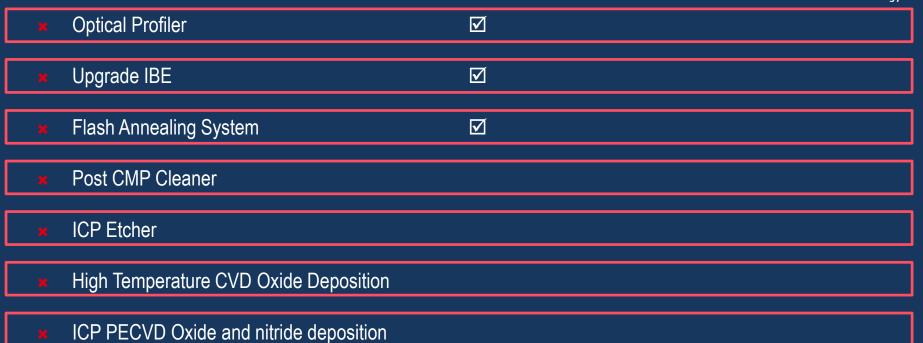
- Submission deadline SNSF R'Equip :15.05.2019
- Prof. Guillermo Villanueva
- + Deposition of dielectric materials
- Multilayers & Bragg reflectors
- + Co-sputtering of metals, nitrides & oxides







Tools under evaluation & Budget requests for 2019





EPFL Center of

MicroNanoTechnology

Tools to be transferred from other/closing labs



 LPCVD Furnace - ATV PEO 603 	
 EBL System - Raith 150 	
 Mask Aligner - SUSS MA/BA8 	
 Mask Aligner - SUSS MJB4 	
 Wafer Bonder - EVG 520 	
 Wafer Bonder - EVG 501 	



A bit of history



EPFL turns 50 !

CMi turns 20 !



EPFL-CMi | May 7th 2019 17

A bit of history



EIDGENÖSSISCHE TECHNISCHE HOCHSCHULE LAUSANNE POLITECNICO FEDERALE LOSANNA SWISS FEDERAL INSTITUTE OF TECHNOLOGY



CONFIDENTIEL

Conseil des Ecoles Polytechniques Fédérales Conférence présidentielle du 12.12.1996

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Rapport

sur le développement de la microtechnique

et sur la création d'un centre

de microtechnologie à l'EPFL

EPFI	RAPPORT AU CEPF SUR LA	MICROTECHNIQUE
10	LE CALENDRIER	
La re	éalisation du Centre de microtechnologie suit le calendrier sui	vant :
•	Approbation par les Chambres fédérales de la construction du bâtiment de microtechnique (BM), y compris la salle blanche, Message 94	Décembre 1994
•	Début des travaux de gros œuvre	Janvier 1996
•	Approbation du plan financier pour le BM	Janvier 1996
•	Révision et approbation du plan financier pour le BM	Juillet 1996
•	Approbation de l'extension du BM, y compris le crédit d'équipements pour la microtechnique, Message 96	
	 par le Conseil National 	24 septembre 1996
	- par le Conseil des Etats	2 décembre 1996
•	Début de la construction du CMI	Juin 1997
•	Fin de la construction du CMI	Mars 1998
•	Installation, qualification, mise en service des équipements du CMI	Novembre 1998

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Task Force Microtechnique

Rapport final

destiné au Conseil d'administration du CSEM au Conseil d'Etat du Canton de Neuchâtel à l'Office fédéral de l'éducation et de la science au Conseil des EPF

The creation of the CMi was part or the development of the "Microtechnique" at EPFL. It was approved by the Swiss Parliament in 2 messages, one in 94 and one in 96. The cleanroom was part of the first message and the scientific equipment was part of the second message. A task force was established in order to elaborate a common vision of the Microtechnique beyond 2000 between: the president of the CEPF, the president of the EPFL, the director of the CSEM, a representative of the UNINE.

Dr S. Bieri (Présidence) Prof. J.-C. Badoux Dr P. Pfluger Dr J.-D. Perret

Neuchâtel, le 19 décembre 1996



Lausanne, le 25.11.96

A bit of history



DIRECTION

CE-Ecublens CH-1015 LAUSANNE TÉLÉPHONE: 021 - 693 35 76 TÉLÉFAX: 021 - 693 35 74 ÉCOLE POLYTECHNIQUE FÉDÉRALE DE LAUSANNE

SEANCE DE DIRECTION DE L'EPFL

du 18 mai 1998

Sur proposition du Directeur de la planification et de la recherche et du Chef du Département de microtechnique, après consultation des personnes concernées, la Direction

décide :

- Le règlement du Centre de microtechnologie (CMI) daté du 13 mai 1998 est approuvé.
- Cette information est communiquée aux chefs de département, aux professeurs du DMT, aux membres du Conseil scientifique du CMI, au directeur et au directeur opérationnel du CMI, aux chefs de service : SP-R, SB, SP, SF.

NAU Prof. J.-C. BADOUX

Président

Dr.I.- I PALTENGHI Directeur de la Planification et de la Recherche

EPFL - CENTRE DE MICROTECHNOLOGIE (CM	(IN																													
	1																													
PLANNING DE MISE EN ROUTE DE LA SAL	LEE	BLA	NCI	HE (SB)																		AL	Rev	. 6	.0/	26.	02.9	8
										-												-								
Année:	98	98	98	98	98	98	98	98	98	98	98	98	98	98	98	98	98	98	99	99	99	99	99	99	99	99	99	99	99	99
Mois:	S	S	S	S	0	0	0	0	0	Ν	N	N	N	D	D	D	D	J	J	J	J	F	F	F	F	М	М	М	Μ	М
Semaine:	36	37	38	39	40	41	42	43	44	45	46	47	48	49	50	51	52	1	2	3	4	5	6	7	8	9	10	11	12	13
Acceptance de la salle blanche	E																													
Réception et placement équipements		xx	xx	xx																										
Connexion équip's électricité, eau, gaz, .			xx	хх	хх	xx	xx								-															
1er. training sécurité			xx																											
Mise en serv. des équip's, training opérat.				xx	xx	xx	xx	xx	xx	xx	xx																			
Installation procédés						xx																								
Création blocs procédés standard de base											xx	xx	xx	xx	xx															
Elab. & test procédures d'accès à la SB															xx	xx														
1er. training équipements																xx		xx	xx	xx										
SB disponible 1ers. projets recherche																					Е									
Préparation wet benches Prettl												xx	xx	xx	xx	xx														
Installation wet benches Prettl																		xx	xx	xx										
Arrêt Labo microstructuration																					Е									
Déménagement équip's vers salle blanche																					x	xx								
Connexion équip's - électricité, eau, gaz,																							XX	xx						
Mise en service équip's, training																									XX					
Installation procédés																										xx				
Création blocs procédés standard de base																											xx			
SB disp. pour enseignement et recherche																												E	5	

The rules of the CMi were approved by the direction of the the EPFL on May 18th, 1998. The cleanroom opened to users in March 1999.

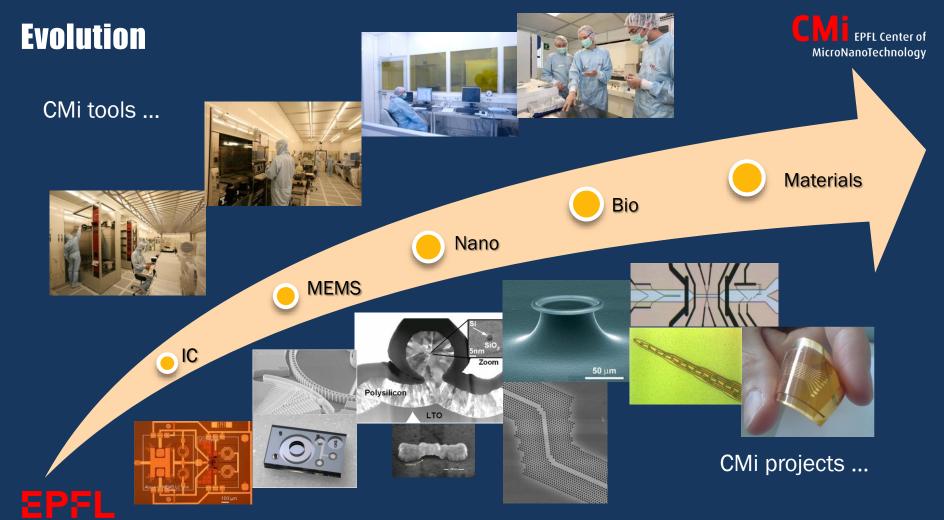
EPFL

Historical Milestones



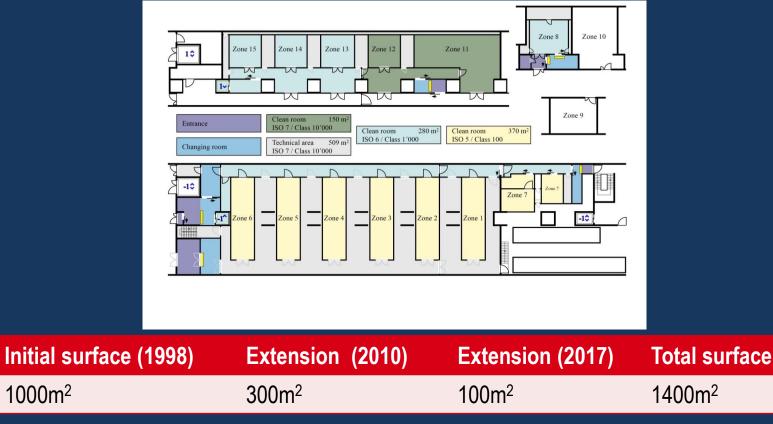
IC & MEMS 1998	CMi created in 1998 & Cleanroom opened in March 1999 Basic Microelectronics processes MEMS processes like Deep silicon etching & SU-8
Nano 2007	 Electron Beam Lithography acquired in 2007 Focused Ion Beam in 2004 Atomic Layer Deposition in 2011
Cleanroom extension 24/7 2010	 Cleanroom extension opened in 2010 for more flexibility and cheaper access Operated now in 24/7 mode since 2012 PDMS, SU-8, Chemistry, Metrology, Non-conventional processes
Materials Diversity 2013	Ion Beam EtchingChemistry
More Capabilities & Renewal 2014	 Photolithography: Mask Fabrication – Coater & Developer – Mask Aligner PVD & ALD & PLD Dry Etching
DUV Stepper lithography 2019	 DUV stepper Renewal of aging tools & Adding new capabilities Envision the acquisition of a second EBEAM at the horizon of 2022





Cleanroom







1000m²

Capital investment

• Processing Equipment

Scientific Equipment Level -1		28 MCHF
Scientific Equipment Level +1		3 MCHF
	Total	31 MCHF

Cleanroom Infrastructures

Cleanroom Infrastructures Level -1	12 MCHF
Cleanroom Infrastructures Level +1	7 MCHF
Total	19 MCHF

• Total 50MCHF





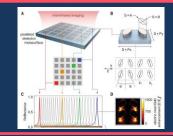




🗴 Prof. Altug

- **x** Science (8 June 2018)
- DOI: 10.1126/science.aas9768

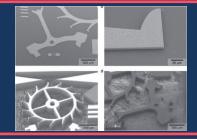
Bionanophotonic systems for molecular detection



Prof. Quack

Diamond mechanical parts

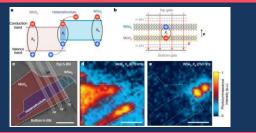
- Nature Microsystems & Nanoengineering (18 June 2018)
- DOI 10.1038/s41378-018-0014-5



× Prof. Kis

- × Nature (16 August 2018)
- **x** DOI : 10.1038/s41586-018-0357-y

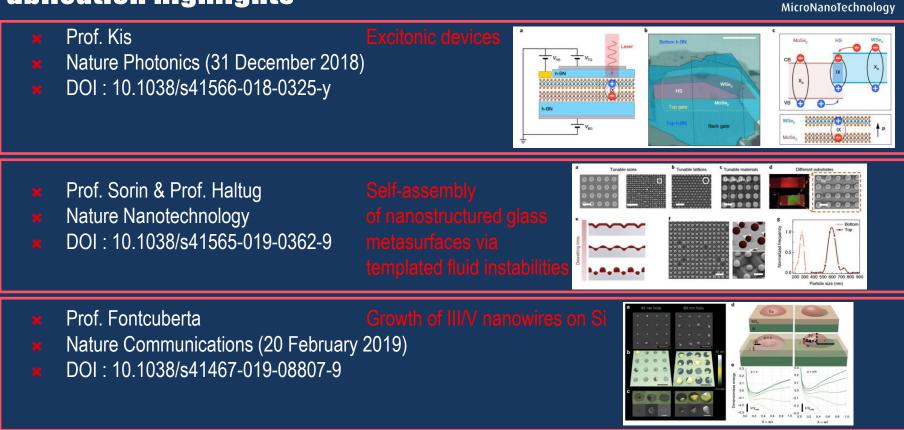
Excitonic devices working at room temperature based on atomically thin semiconductor



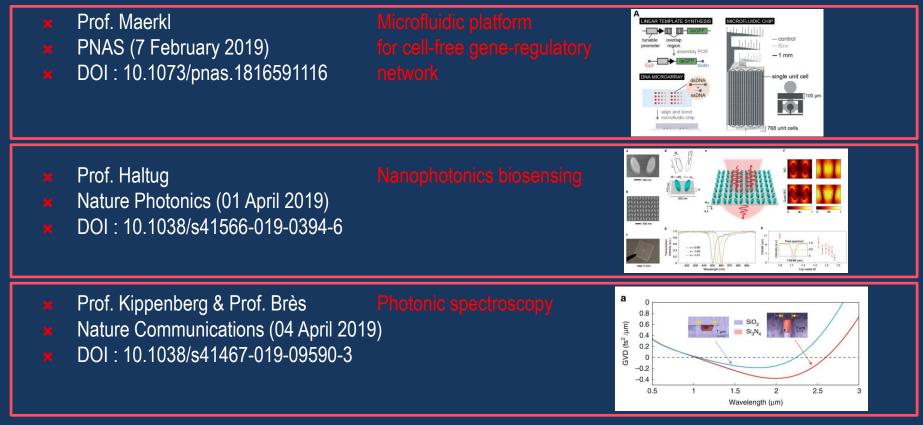


EPFL









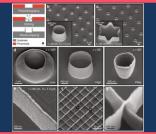
EPFL



Prof. Renaud

3D nanostructure manufacturing

- Nature Microsystems & Nanoengineering (22 April 2019)
- DOI 10.1038/s41378-019-0052-7





Press releases



- Prof. Sakar
- ERC Starting Grants 714609
- ROBOCHIP
- **x** 1 March 2017 28 February 2022

Robotic micromanipulation systems o perform automated operations on 3D biological samples



- Prof. Kippenberg
- ERC Advanced Grant
- **ExCOM-cCEO**
- Announced 21 March 2019

Extremely Coherent Mechanical Oscillator and circuit Cavity Electro-Optics

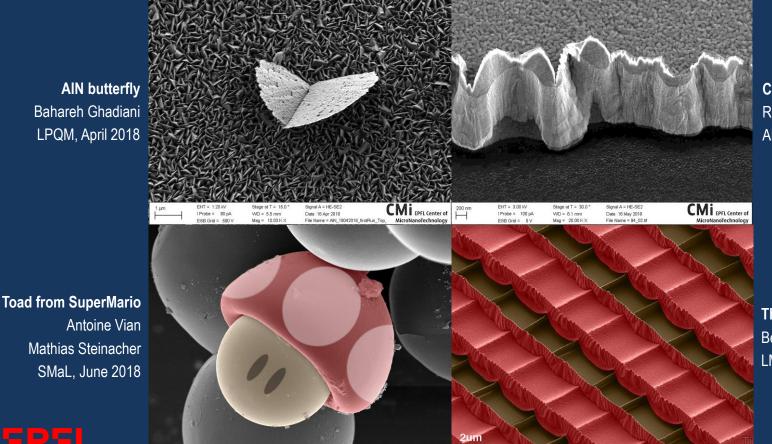
- **Prof.** Kippenberg
- ERC Proof of Concept Grant
- PhoMEC
- Announced 03.05.2019

Photonic integrated optical frequency combs



Picture of the month





Cliffs of Etretat Richard Meunier Aleva, May 2018

The opera house Benoît Desbiolles LMIS4, July 2018

Picture of the month



Attack of the Gnomes Simon Escobar Steinvall, LMSC, August 2018 Signal A = InLen CMi EPFL Center of MicroNanoTechnology Probe = 100 oA Date :2 Aug 2018 WD = 51 mmSB Grid = Date :21 Nov 2018 EHT = 200 k Date :19 Oct 2018 2 µm EHT = 1.00 kV Signal A = SE2 EPFL-CMI Mag = 3.27 K X EPFL-CMI Mag = 4.86 K X

WD = 6.5 mm

Stage at T = 21.0 ° File Name = 2_1_58.tif

WD = 7.7 mm

Stage at T = 0.0

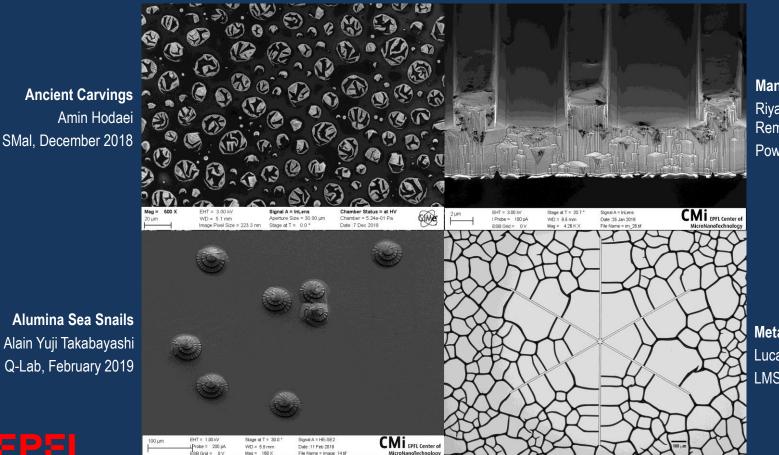
Strawberry & Mushroom Teodoro Graziosi Q-Lab, September 2018

Rare coral Anastasiia Glushkova LPMC, November 2018

MgO urchin on Mg coral Matthieu Rüegg Lorenz Hagelüken LMIS1, October 2018



Picture of the month



Manhattan Skyline Riyaz Mohammed Abdul, Remco van Erp PowerLab, January 2019

C M EPFL Center of

MicroNanoTechnology

Metallic spider web Lucas Güniat, LMSC, March 2019

Artistic image





Catherine Leutenegger, photograph (made with the Nanoscribe tool in CMi)

Abstracts 2019

• 220 posters collected in the brochure







Program

- Very exciting program
- 10 presentations
- Spanning an exceptionally broad range
- Try to be different every year
- Not always invite the heavy users
- Emphasize on the new Professors @ EPFL
- Sometimes also some exotic users
- One common point:

EPFL

- MicroNanoFabrication





MicroNanoFabrication Annual Review Meeting

Date: Tuesday May 7th, 2019 Time: 09h30 – 17h00 Place: EPFL, Forum Rolex Learning Center, RLC E1 240

Program:

09h30-10h00	Coffees and Croissants, Distribution of Badges and Proceedings
10h00-10h15	Philippe Renaud & Philippe Flückiger (https://cmi.epfl.ch/), Introduction
10h15-10h30	Heike Riel, IBM Fellow, Department Head Science & Technology, IBM Research, Rüschlikon, Title of the talk to be announced soon
10h30-10h45	Vivek Subramanian (https://laft.epfl.ch/), Additive fabrication of electronics and MEMS: From printable materials to integrated systems
10h45-11h00	Philip Moll. (https://qmat.epfl.ch/), Quantum materials: new electronic functionality on the micron-scale
11h00-11h30	Break
11h30-11h45	Olivier Martin, (https://nam.epfl.ch/), Alloyed nanostructures and metasurfaces
11h45-12h00	Guillermo Villanueva, (https://nems.epfl.ch/), Piezoelectric suspended microchannel resonators
2h00-12h15	Selman Sakar, (https://microbs.epfl.ch/), Soft robotic microsystems for biomedical applications
2h15-14h30	Lunch & Poster Session
14h30-14h45	Michael Graetzel, (https://lpi.epfl.ch/), Mesoscopic photosystems for the generation of electricity and fuels from Sunlight
14h45-15h00	Sandro Carrara, (http://iowww.epfl.ch/~scarara/), Very recent advances on memristive sensors: the born of a new field of research
15h00-15h30	Break
15h30-15h45	Hatice Altug, (https://bios.epfl.ch/), Nanophotonic metasurfaces for next- generation biosensors
15h45-16h00	Yusuf Leblebici, (https://sm.epfl.ch/), Next-generation non-volatile memory technologies and 3D integration
	Cocktails & Poster Session

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Thank you to the CMi staff







Enjoy the conference





